

Abstract

A defect detection system, method and apparatus, a device, and a storage medium are provided. The system comprises: a stage, an illumination subsystem, an imaging subsystem, a sensor, and a processor, wherein the illumination subsystem is connected to the processor, and the sensor is connected to the processor; the imaging subsystem is arranged above the stage and configured to image an inspected object placed on the stage; the illumination subsystem is arranged on an incident optical path of the imaging subsystem; the sensor is arranged on an imaging optical path of the imaging subsystem; and a target area in the inspected object is located within an irradiation area of the illumination subsystem.

[Fig. 1]